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## U.S. PATENT DOCUMENTS

[illegible]

## FOREIGN PATENT DOCUMENTS

[illegible]

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

M	M	C. Kaufman et al., "Characterization of Material and Structure Defects on Micromechanical Scanners by Means of Frequency Analysis," <u>Proceedings of Micro Materials</u> (1995), pg. 443 ff
M	M	P. Enoksson et al., "A Silicon Resonant Sensor Structure for Coriolis Mass-Flow Measurements," <u>Journal of Micromechanical Systems</u> , Vol. 6, No. 2, (June 1997), pgs. 119 through 125
M	M	J. Choi et al., "Silicon Angular Rate Sensor by Deep Reactive Ion Etching," <u>Proceedings of the International Symposium on Microsystems, Intelligent Materials and Robots</u> (Sendai, Japan, 1995), pgs. 29 through 32

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